

# EE143 – Fall 2016 Microfabrication Technologies

## Lecture 14: MEMS Process

Prof. Ming C. Wu

wu@eecs.berkeley.edu

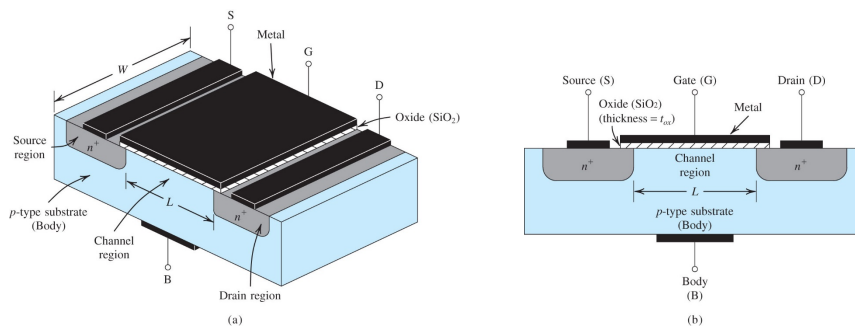
511 Sutardja Dai Hall (SDH)



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## MOSFET



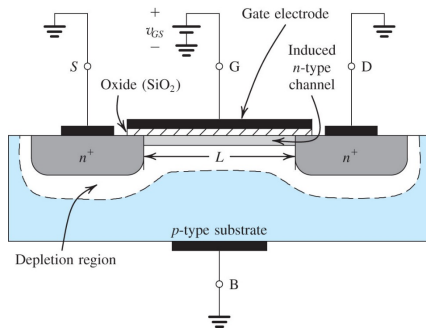
- **MOSFET: metal-oxide-semiconductor field effect transistor**
- **Typically**
  - Channel length:  $L \sim 10 \text{ nm to } 0.35 \mu\text{m}$ ,
  - Channel width:  $W \sim 0.05 \mu\text{m to } 100 \mu\text{m}$ ,
  - Oxide thickness:  $t_{ox} \sim 1 \text{ to } 10 \text{ nm}$



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## NMOSFET (or simply NMOS)



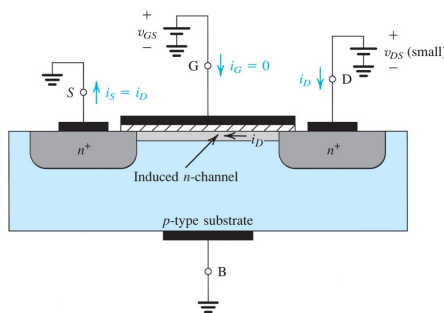
- **N-channel MOSFET**
  - Current conducted by electrons
- **3 terminal device**
  - Source (S): n+ (heavily n-type)
  - Drain (D): n+
  - Gate (G): metal deposited on insulator above channel
- **Substrate (called "Body") is a 4<sup>th</sup> terminal**
  - Substrate is p-doped
- **Electrons is induced in channel when a positive gate voltage is applied**
- **Electrons moves from Source to Drain**
  - Current flows from D to S



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## Creating a "Channel" for Current Flow



MOS is a capacitor across an insulator (oxide)  
When a positive voltage is applied at Gate, electrons are induced under the gate.

At "threshold", sufficient number of electrons form a "channel" between Source and Drain, forming a conductive channel.

Total charge in the channel:

$$|Q| = C_{ox} \cdot WL \cdot (v_{GS} - V_t)$$

where  $C_{ox} = \frac{\epsilon_{ox}}{t_{ox}}$  is oxide capacitance

per unit area

$$\epsilon_{ox} = 3.9\epsilon_0 = 3.9 \times 8.854 \times 10^{-12} \text{ F/m}$$

$W$ : gate width

$L$ : gate length

$V_t$ : Threshold voltage

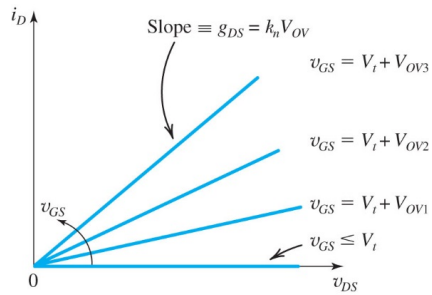
$v_{GS} - V_t \equiv v_{OV}$  is called "Overdrive Voltage"



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## Current at Small $v_{DS}$



When  $v_{OV} = v_{GS} - V_t > 0$ , a channel is formed between Source and Drain.

Linear charge density in channel:

$$\frac{|Q|}{L} = C_{ox} W \cdot v_{OV}$$

Electric field along the channel

$$|E| = \frac{v_{DS}}{L}$$

Drain current = charge density x velocity:

$$i_D = \frac{|Q|}{L} v_n = \frac{|Q|}{L} \mu_n |E| = C_{ox} W \cdot v_{OV} \mu_n \frac{v_{DS}}{L}$$

$$i_D = \mu_n C_{ox} \frac{W}{L} v_{OV} v_{DS}$$

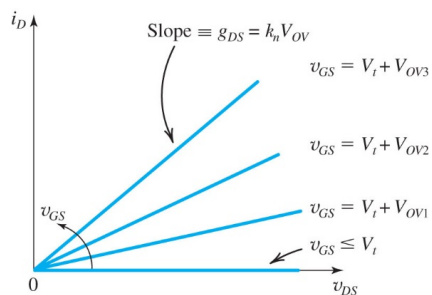
At small  $v_{DS}$ , the transistor is like a gate-controlled variable resistor



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## Current at Small $v_{DS}$



$$i_D = \mu_n C_{ox} \frac{W}{L} v_{OV} v_{DS}$$

$$= k_n' \frac{W}{L} v_{OV} v_{DS}$$

$$= k_n v_{OV} v_{DS}$$

where

$$k_n' = \mu_n C_{ox} : \text{process transconductance parameter}$$

$$k_n = \mu_n C_{ox} \frac{W}{L} : \text{MOSFET transconductance parameter}$$

parameter

MOSFET behaves like a linear resistor

$$r_{DS} = \frac{v_{DS}}{i_D} = \frac{1}{k_n v_{OV}}$$

Resistance value can be changed

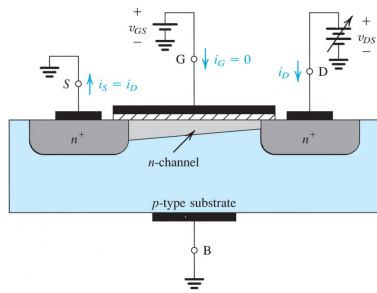
by gate voltage (overdrive voltage)



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## Triode Region ( $v_{DS} < v_{OV}$ )



As  $v_{DS}$  increases, the potential in the channel is no longer a constant. Assume the channel is  $v(x)$ :

$$i_D = C_{ox} W (v_{GS} - v(x) - V_t) v_n(x)$$

$$v_n(x) = \mu_n |E(x)| = \mu_n \frac{dv(x)}{dx}$$

Note:  $i_D$  is still constant along the channel (think Kirchhoff's Current Law)

Integrate along the channel

$$\int_{x=0}^{x=L} i_D dx = \int_{x=0}^{x=L} \left( C_{ox} W (v_{GS} - v(x) - V_t) \mu_n \frac{dv(x)}{dx} \right) dx$$

Change of variable on right-hand side:  $x \rightarrow v$

$$i_D L = \int_{v=0}^{v=v_{DS}} \left( C_{ox} W (v_{OV} - v) \mu_n \right) dv$$

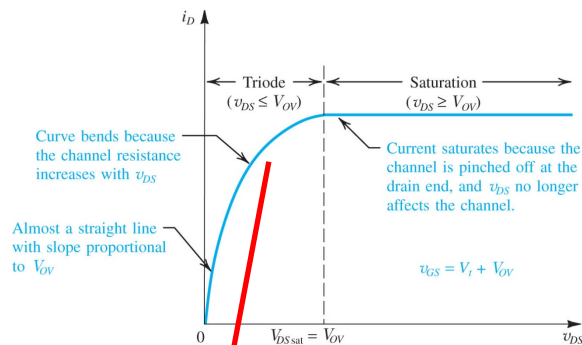
$$i_D = \mu_n C_{ox} \frac{W}{L} \left( v_{OV} v_{DS} - \frac{1}{2} v_{DS}^2 \right)$$



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## Triode Region ( $v_{DS} < v_{OV}$ )



When  $0 \leq v_{DS} \leq v_{OV}$

$$i_D = \mu_n C_{ox} \frac{W}{L} \left( v_{OV} v_{DS} - \frac{1}{2} v_{DS}^2 \right)$$

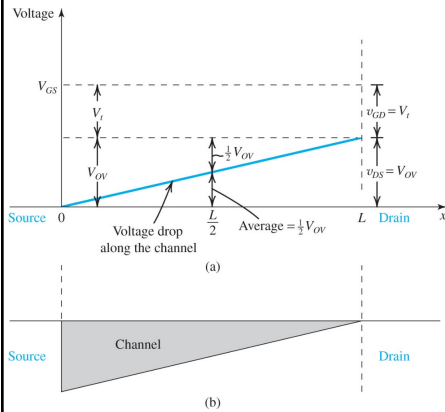
This is called the "Triode Region"



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## Pinch-Off



The channel potential at the drain side is  $v_{DS}$ .

When  $v_{DS} = v_{OV}$ , the local charge density there

$$\frac{|Q|}{\text{area}} = C_{ox} (v_{GS} - v_{DS} - V_T) = C_{ox} (v_{OV} - v_{DS}) = 0$$

So the channel is "pinched off" near the Drain.

Once the channel is pinched off, the drain current remains constant:

$$i_D = \frac{1}{2} \mu_n C_{ox} \frac{W}{L} v_{OV}^2$$

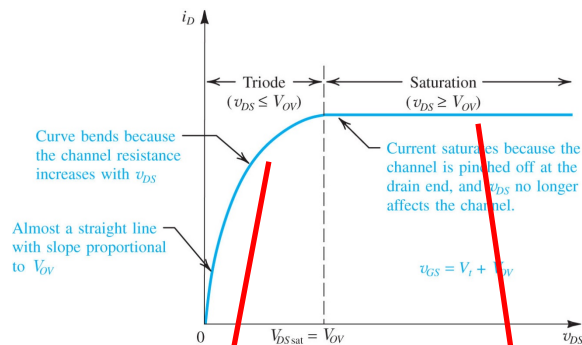
This region,  $v_{DS} > v_{OV}$ , is called "Saturation"



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## Saturation Region ( $v_{DS} > v_{OV}$ )



When  $0 \leq v_{DS} \leq v_{OV}$

$$i_D = \mu_n C_{ox} \frac{W}{L} \left( v_{OV} v_{DS} - \frac{1}{2} v_{DS}^2 \right)$$

This is called the "Triode Region"

When  $v_{DS} > v_{OV}$ ,

$$i_D = \frac{1}{2} \mu_n C_{ox} \frac{W}{L} v_{OV}^2$$

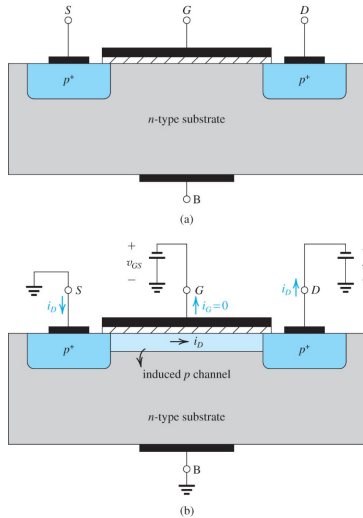
This is called "Saturation Region"



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## PMOSFET (or simply PMOS)



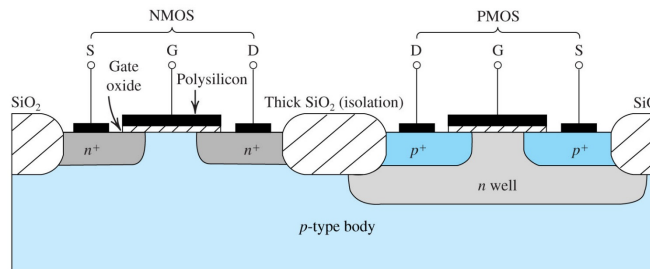
- **P-channel MOSFET**
  - Current conducted by holes
- **3 terminal device**
  - Source (S): p+ (heavily p-type)
  - Drain (D): p+
  - Gate (G): metal deposited on insulator above channel
- **Substrate (called “Body”) is a 4<sup>th</sup> terminal**
  - Substrate is n-doped
- **Holes is induced in channel when a negative gate voltage is applied**
- **Holes moves from Source to Drain**
  - Current flows from S to D



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## CMOS (Complementary MOS)



- **CMOS is the prevalent IC technology today**
- **Since NMOS and PMOS are formed on oppositely doped substrates, one of the transistor needs to be placed in a “well”**
- **PMOS is placed in an “n well” here.**
- **Alternatively, NMOS can be placed in p well**



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